

# Properties of Epitaxial Ilmenite Hematite Magnetic Semiconductor Films

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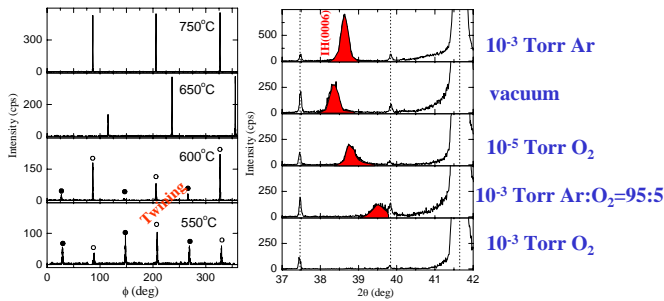
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## Objective

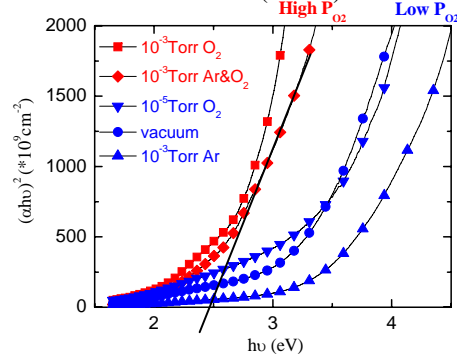
- Grow epitaxial Ilmenite-Hematite (IH) films.
- Characterize and understand magnetic, electrical and optical properties
- Study spin transport properties
- Fabricate and evaluate p-n and tunnel junction devices

## X-ray diffraction of IH (x=0.33) films



- Enough thermal energy needed for ions to migrate to the most epitaxially ordered lattice position
- Higher oxygen pressure leads to smaller lattice constant
- Films grown in high oxygen pressure lose crystallinity

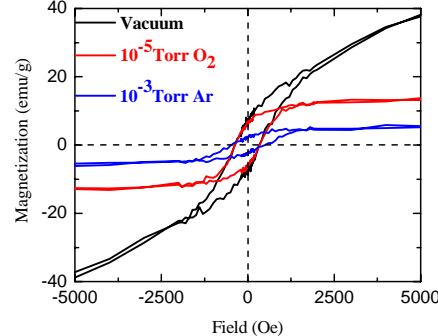
## UV of IH(x=0.33) films



- Oxygen vacancy increases energy band gap

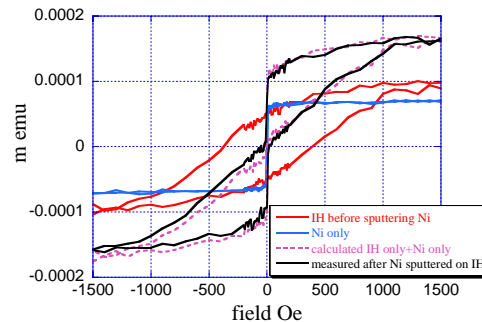
	Ilmenite-Hematite(IH) (1-x)FeTiO <sub>3</sub> -xFe <sub>2</sub> O <sub>3</sub>	(Ga,Mn)As	doped ZnO
Curie Temperature	>500 K (dependent on composition) ~1000 K	<110K	300K ~400K
Magnetic Moment	4μ <sub>B</sub> /Fe 147 emu/g (>7000 Gauss)	4.46μ <sub>B</sub> /Mn (5K) 400 Gauss (5K)	2μ <sub>B</sub> /Co (6K) 20.8 emu/g
Semiconductor type	n or p (dependent on composition)	p	P
E <sub>g</sub>	~3.5 eV	<1.5 eV	~3.35 eV
Transparent	Yes	No	Yes <sup>a</sup>
Mobility/ carrier concentration	<1 cm <sup>2</sup> V <sup>-1</sup> s <sup>-1</sup> /	High/3*10 <sup>20</sup> cm <sup>-3</sup> (@ 1.5K)	17.9 cm <sup>2</sup> V <sup>-1</sup> s <sup>-1</sup> /2.9*10 <sup>20</sup> cm <sup>-3</sup> 3.5*10 <sup>20</sup> cm <sup>-3</sup>

## Magnetic moment of IH (x=0.33) films



- Higher crystalline ordering → higher magnetic ordering
- Oxygen vacancy effect on magnetic moment ---??

## Magnetic interaction between IH and other ferromagnetic layers



- Moment of IH and Ni layers switch individually

## PLD Parameters for IH Film Growth

Excimer Laser:

KrF (248 nm, 20ns, 2 Hz, 1.7J/cm<sup>2</sup>, ~5000 Pulses)

Chamber base pressure: 10<sup>-7</sup> Torr

Substrate: Al<sub>2</sub>O<sub>3</sub> (lattice mismatch ~7%) c-cut

Target to substrate distance: 5 cm

In-situ annealing: 1 hour

Substrate Temperature: 550-750°C

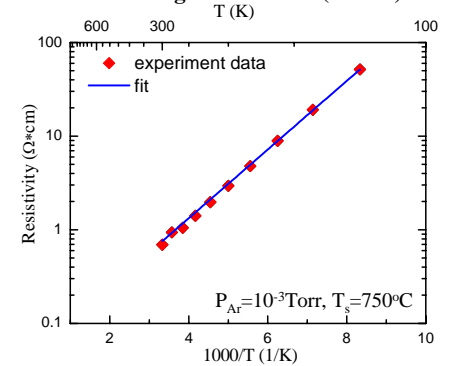
Ambient gas: vacuum

Ar (10<sup>-3</sup>Torr)

O<sub>2</sub>(10<sup>-5</sup>Torr, 10<sup>-3</sup>Torr)

mixed Ar & O<sub>2</sub>(in 95:5 ratio, 10<sup>-3</sup>Torr)

## Semiconducting nature of IH (x=0.33) film



- Transport activation energy E<sub>a</sub>=0.15eV by using Wilson's formula ρ=ρ<sub>0</sub>exp(E<sub>a</sub>/2kT)

## Conclusion

- Epitaxial IH film quality highly depends on the oxygen pressure and substrate temperature ---Best deposition condition: 750°C, 10<sup>-5</sup> Torr O<sub>2</sub>
- IH film (x=0.33) has ferromagnetic and semiconducting nature
- Oxygen vacancy increases the energy band gap

## Future Work

- Investigate magnetic behavior & improve magnetic ordering
- First-principle calculation of IH Band structure, understand electronic, magnetic and optical properties changing with oxygen vacancy
- Investigate magnetic exchange of IH layers in contact with other ferromagnetic layers